

OS08 Nano-scale surface finishing

OS08-02 Development of a 3-DoF topology- optimized compliant mechanism for shear-thickening fluid polishing

Airi Umezawa, Ashwani Pratap and Anthony Beaucamp

OS08-03 Investigation of surface characteristics of mirror-finished surfaces using polycrystalline sintered diamond ball end mill

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King Mongkut's University of Technology Thonburi

OS08-04 Removal characteristics of single crystal diamond (111) substrate by vacuum-ultraviolet assisted polishing

Sora Ninomiya and Akihisa Kubota

OS08-05 Polishing methods for large-area mosaic diamond substrate

Keiji Kasamura, Yusuke Shirayanagi, Hiroki Toyoda, Shingo Tomohisa, Takashi Takenaga and Akihisa Kubota

OS08-06 Fluid jet polishing of stainless-steel optical molding inserts

Ashish Kumar, Ashwani Pratap and Anthony Beaucamp
Keio University

OS08-07 Optimization of oscillation control by simulation for uniform polishing amount in ECMP processing of SiC wafers

Aoi Kaneko, Rongyan Sun, Yuji Ohkubo and Kazuya Yamamura

OS08-08 Surface polishing of YAG ceramics using catalyst-referred etching

Yusuke Yoshida, Kiyoto Kayao, Daisetsu Toh, Jumpei Yamada, Kazuto Yamauchi and Yasuhisa Sano
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OS08-09 High-efficiency Polishing of GaN(0001) Substrates Using Catalyst-referred Etching Assisted by Photoelectrochemical Reaction

Kiyoto Kayao, Tatsuya Fukagawa, Daisetsu Toh, Jumpei Yamada, Kazuto Yamauchi and Yasuhisa Sano
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OS08-10 Magnetic Field-assisted Mass Polishing of Optical Glasses
Yee Man Loh, Chunjin Wang, Rui Gao, Lai Ting Ho and Chi Fai Cheung
The Hong Kong Polytechnic University

OS08-11 Correction of Mid- and Low-Spatial Frequency Errors in Silicon Mirrors via Dehydration Polishing
Bing Wu, Shengnan Zhang and Hui Deng
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Yuan Xie and Hui Deng
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OS08-13 Microwave plasma-assisted polishing of polycrystalline diamond
Xinyu Li and Hui Deng
Southern University of Science and Technology

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Chuhong He and Hui Deng
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OS08-15 Chemical-Assisted Magnetic Compound Fluid Polishing of TA1 Capillary Inner Surface
Wentao zhang, Yufen Xue, Yangke Zheng, Hanqiang Wu and Yongbo Wu
Southern University of Science and Technology

OS08-16 Atomic-Level Smoothing of Silicon Surfaces Using a PMMA Plate in Water: Understanding the Chemical Mechanism
Jianli Guo, Satoru Egawa, Hiroto Motoyama and Hidekazu Mimura
the University of Tokyo

OS08-17 Synthesis of nano-sized cerium oxide particles for chemical mechanical polishing of quartz glass and evaluation of their polishing properties
Xianglong Liu, Akihisa kubota, Makoto Tokuda and Tsutomu Mashimo
Kumamoto university

OS08-18 Tip-based nanofabrication on a hydrogen-terminated diamond surface by electrochemistry
Jinyan Tang, Mao Peng, Yangyang Li and Yuan-Liu Chen

OS08-19 Planarization of substrate with metal wiring using catalyst-referred etching -Etching characteristic of wiring metal-

Hiroto Yamasaki, Kiyoto Kayao, Daisetsu Toh, Jumpei Yamada, Kazuto Yamauchi and Yasuhisa Sano
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OS08-20 Highly Efficient Etching of GaN (0001) Substrate by Photoelectrochemical Etching

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OS08-21 Fluid jet polishing of functional structured surfaces

Chunjin Wang, Zili Zhang and Benny C. F. Cheung

OS08-22 Electrochemical shear thickening polishing of single crystal silicon carbide

Mengmeng Shen, Wei Hang, Hongyu Chen, Binghai Lyu and Yunxiao Han
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OS08-23 Fixed-abrasive electrochemical mechanical polishing of single-crystal silicon

Xiaozhe Yang, Shenglong Zhang, Xu Yang, Kazuya Tamamura and Zhuangde Jiang
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